ket No.: 50090-443

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kazunobu MIKI

Serial No.: 09/973,049

Filed: October 10, 2001



Group Art Unit: 2829

Examiner: J. M. Hollington

For:

SEMICONDUCTOR ELEMENT TEST APPARATUS, AND METHOD OF TESTING

SEMICONDUCTOR ELEMENT USING THE APPARATUS

THE COMMISSIONER FOR PATENTS AND TRADEMARKS Washington, DC 20231

Dear Sir:

Transmitted herewith is an Amendment in the above identified application.

No additional fee is required.

Applicant is entitled to small entity status under 37 CFR 1.27

Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	10	20	0	\$18.00 =	\$0.00
Independent Claims	3	3	0	\$84.00 =	\$0.00
	Multiple claims newly presented			\$0.00	
		Fee for extension of time			\$0.00
				\$0.00	
		Total of Above Calculations			\$0.00

П Please charge my Deposit Account No. 500417 in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.

 \boxtimes The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

MCDERMQTT/WILL & EMERY

Scott D. Paul

Registration No. 42,984

600 13th Street, N.W. Washington, DC 20005-3096 (202) 756-8000 SDP:kap Facsimile: (202) 756-8087 Date: March 4, 2003

TECHNOLOGY CENTER 2800

Docket No.: 50090-443

PATENT

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Kazunobu MIKI

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For: SEMICONDUCTOR ELEMENT TEST APPARATUS, AND

METHOD OF TESTING SEMICONDUCTOR ELEMENT

USING THE APPARATUS

AMENDMENT

Box Non-Fee Amendment The Commissioner for Patents and Trademarks Washington, DC 20231

Sir:

The following Amendment and Remarks are submitted in response to the Office Action dated December 4, 2002. Please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 2, first full paragraph, please delete in its entirety and replace with the following:

--Fig. 11 is a side view showing the constitution of the prober 2 while the stage 4 remains in a lowered position. Fig. 12 is a perspective view showing a probe card 1 having the probe needles 7 mounted thereon. Fig. 13 is a top view showing the probe card 1. The prober 2 is equipped with the probe card 1. The probe card 1 has a probe card substrate 12 which supports the plurality of probe needles 7. The prober 2 has a test head 10 which operates in cooperation

